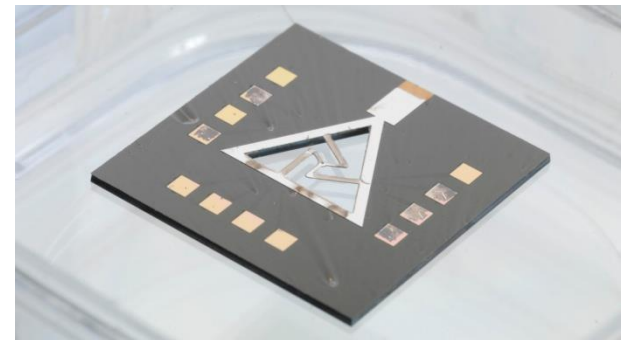
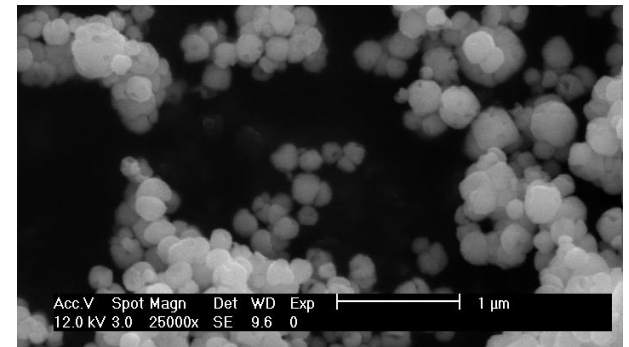
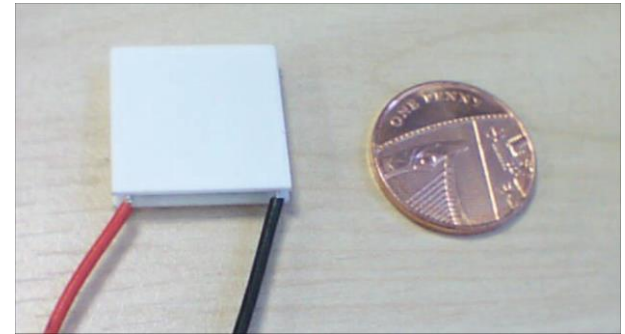


# Towards manufacture of thick film thermoelectric devices

Professor Robert Dorey, Chair of Nanomaterials

# Introduction

- Functional materials
- Towards sustainability through additive manufacturing for micro scale structures
- Impact on synthesis of functional materials
- Impact on processing functional additively manufactured structures



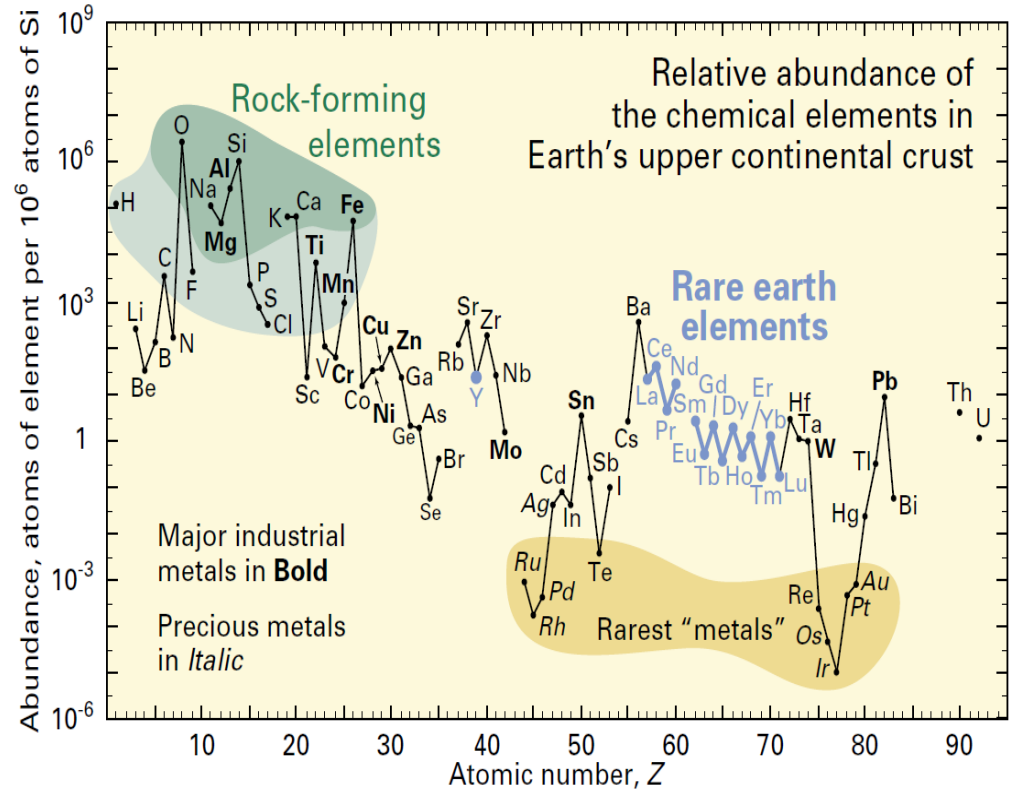
**ENHANCED**

**MASSIVE**  
Functional Materials

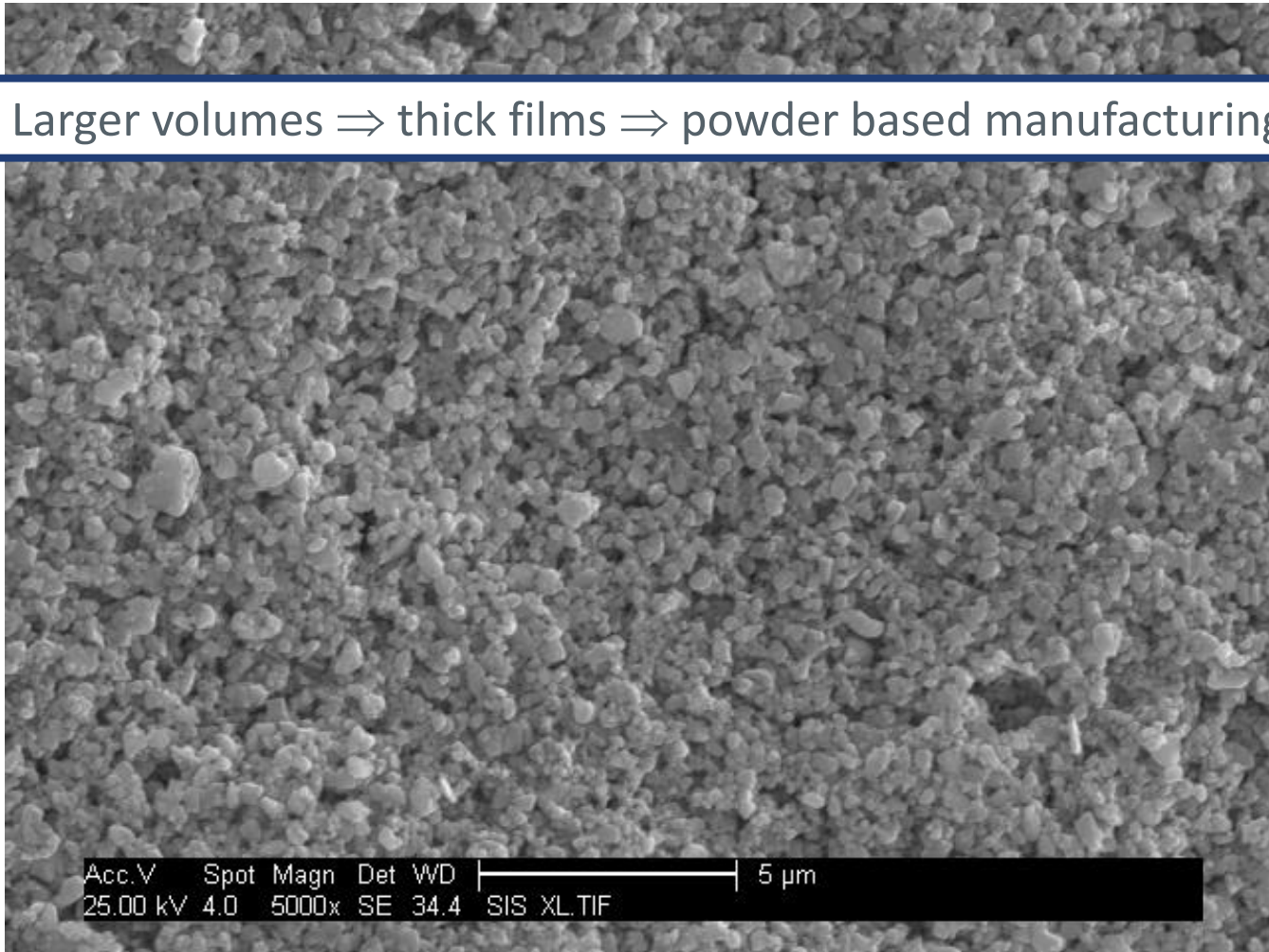
**Innovate UK**  
Technology Strategy Board

**EPSRC**

	Commercial materials	Potential alternative materials
<b>Thermo electrics</b>	SbTe, BiTe, PbTe, SiGe	NaCo <sub>2</sub> O <sub>4</sub> , Mg <sub>2</sub> Si, MnSi <sub>x</sub> , SrTiO <sub>3</sub> , BiSrCoO, FeS, Bi <sub>2</sub> S <sub>3</sub> , Cu <sub>x</sub> S, TiS <sub>2</sub> , ZnO,
<b>Piezo/Pyro/Ferro/Di-electrics</b>	Pb(Zr,Ti)O <sub>3</sub> , PbTiO <sub>3</sub> , PbMgNbO <sub>3</sub>	(K,Na)NbO <sub>3</sub> , (Bi,Na)TiO <sub>3</sub> , LiNbO <sub>3</sub>
<b>Electrode and interconnect structures found in all devices</b>	Pt, Pd, InSnO (ITO), Ni	Al-ZnO, TiN, Y-SrTiO <sub>3</sub> , La-SrTiO <sub>3</sub>



Power  $\Rightarrow$  Larger volumes  $\Rightarrow$  thick films  $\Rightarrow$  powder based manufacturing



*PZT film before sintering*

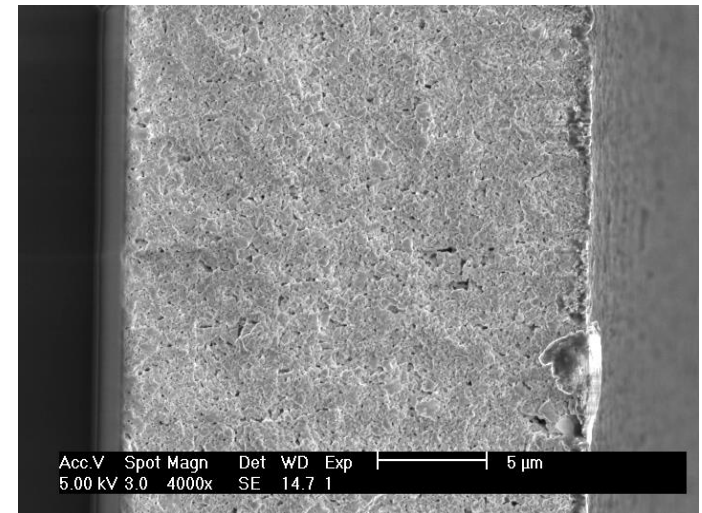
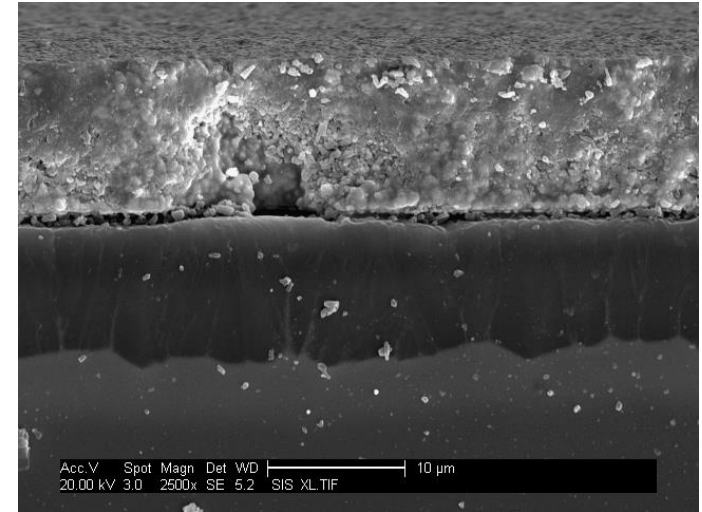
## Temperature induced degradation:

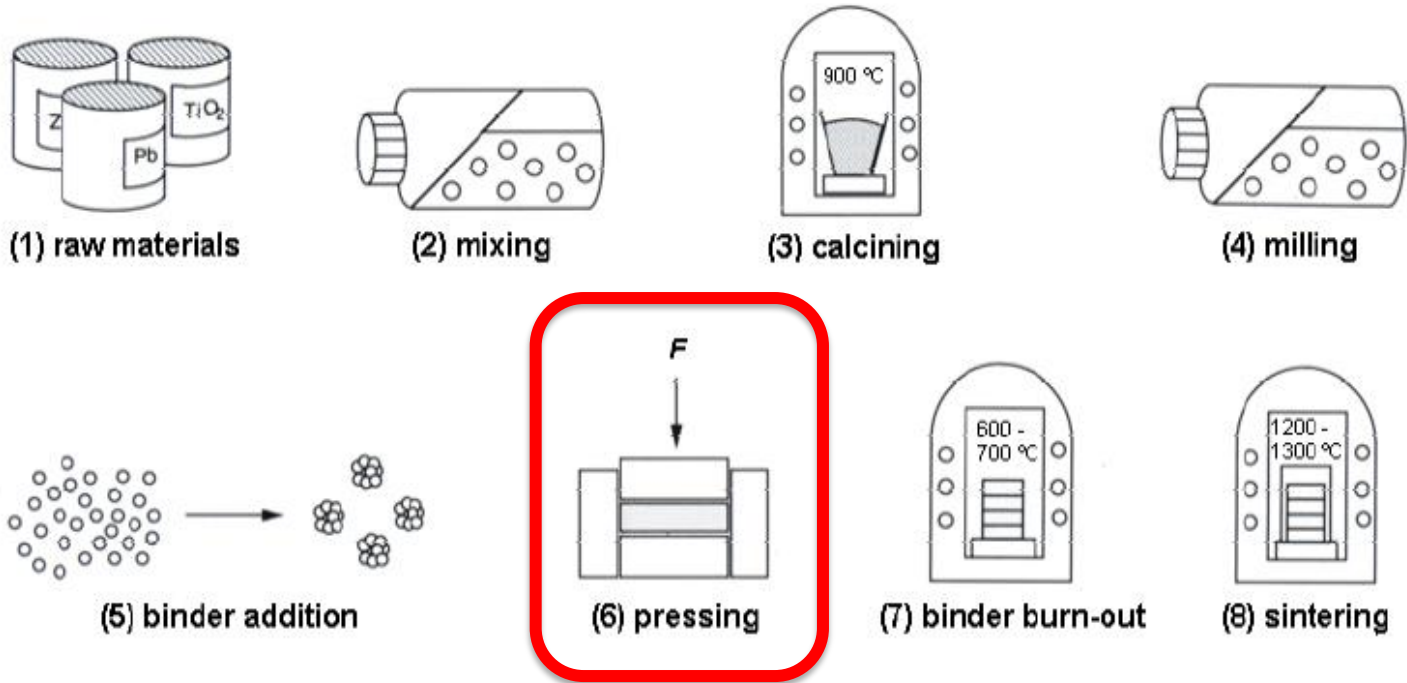
- Interdiffusion
- **Evaporation**
- Degradation

## Solutions:

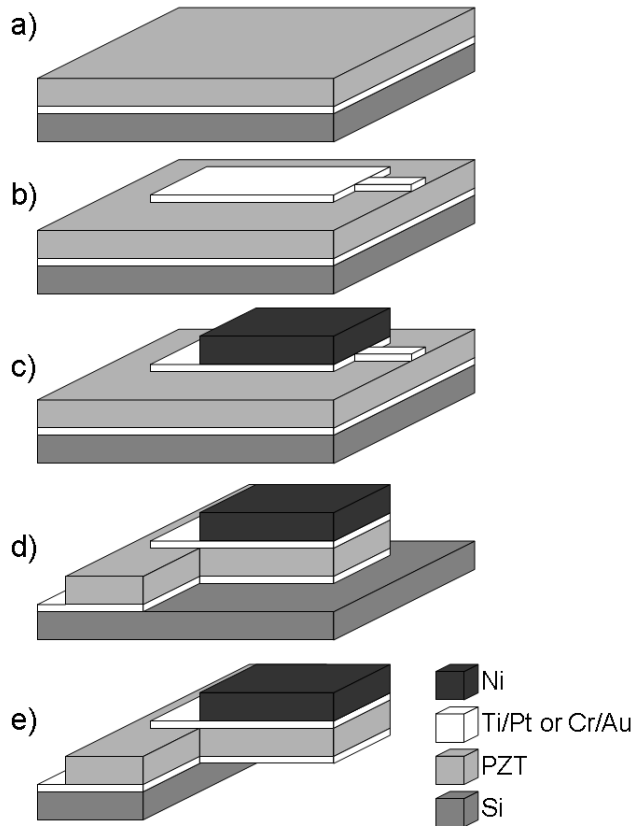
- Low temperature  
e.g. Composite sol gel < 750°C for  
PZT/Si
- Diffusion barrier e.g.  $ZrO_2$

*R.A. Dorey, S.B. Stringfellow, R.W. Whatmore, Effect of sintering aid and repeated sol infiltrations on the dielectric and piezoelectric properties of a PZT composite thick film, J.Euro.Ceram.Soc., 22, 2921-2926, 2002.*

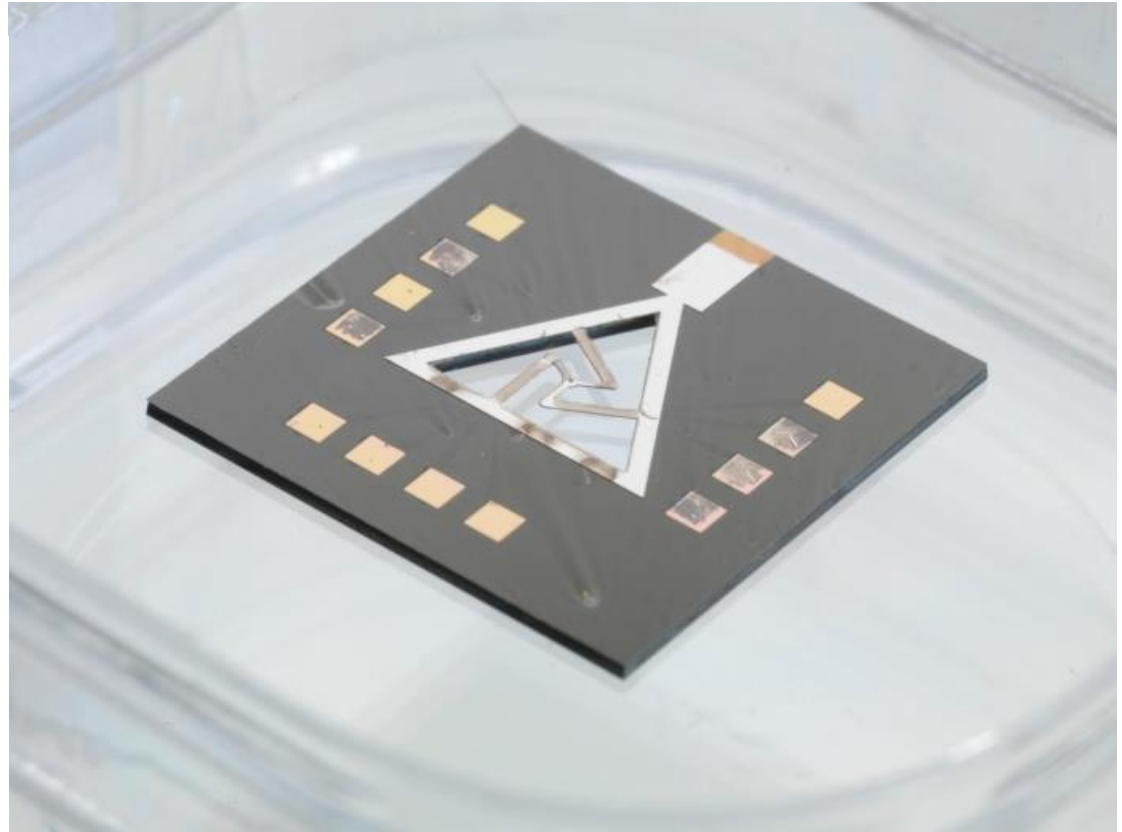




Additive manufacturing techniques

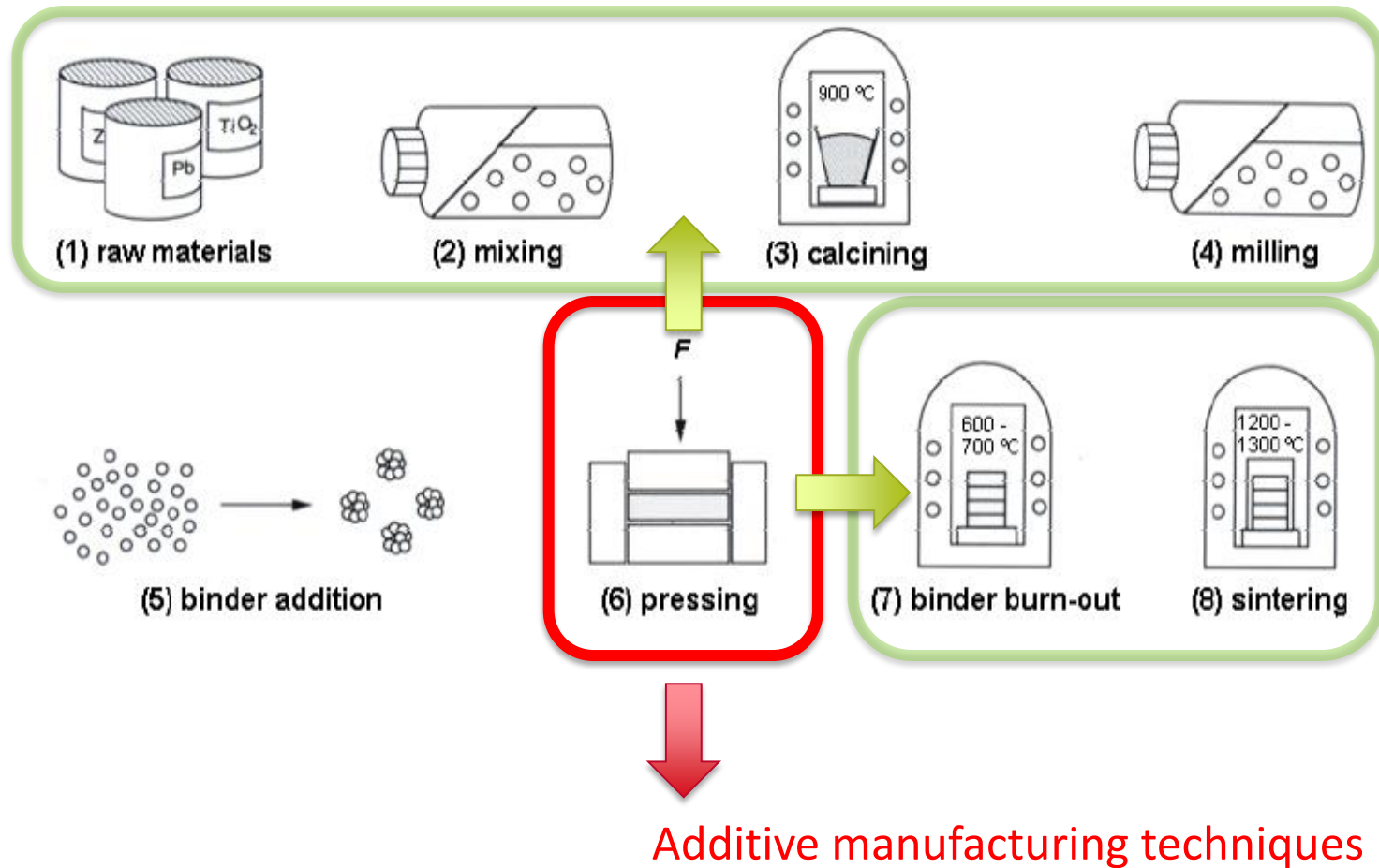


*Fabrication stages*



*Micro coordinate measurement tool  
sensor/actuator*

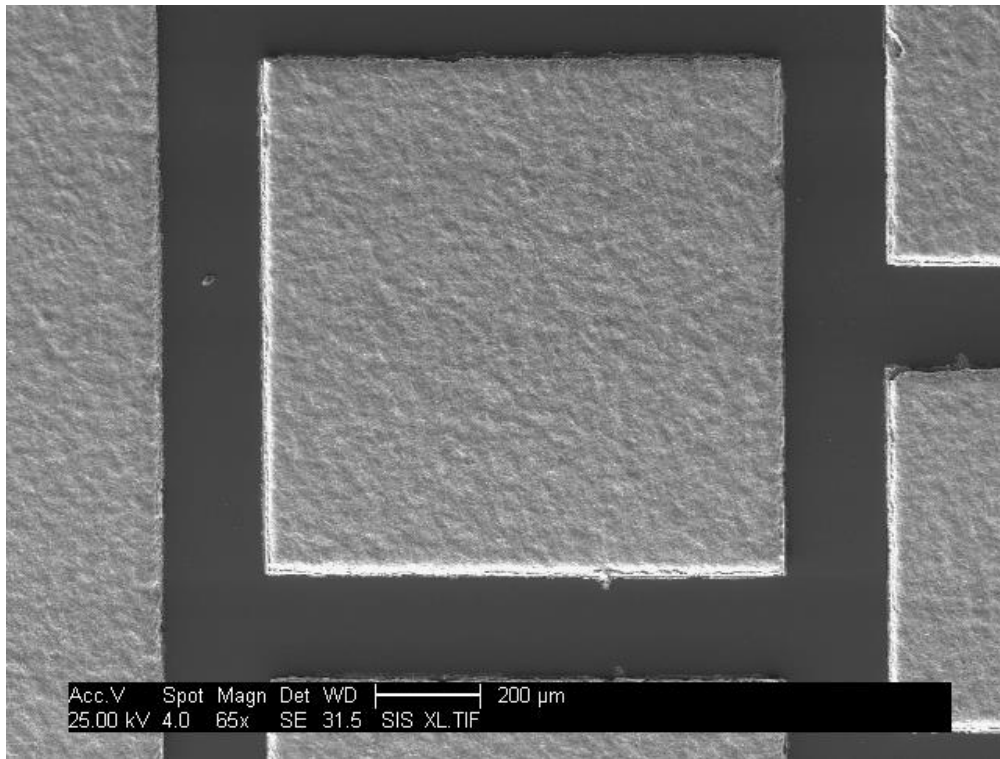
# Additive manufacturing: knock-on effects



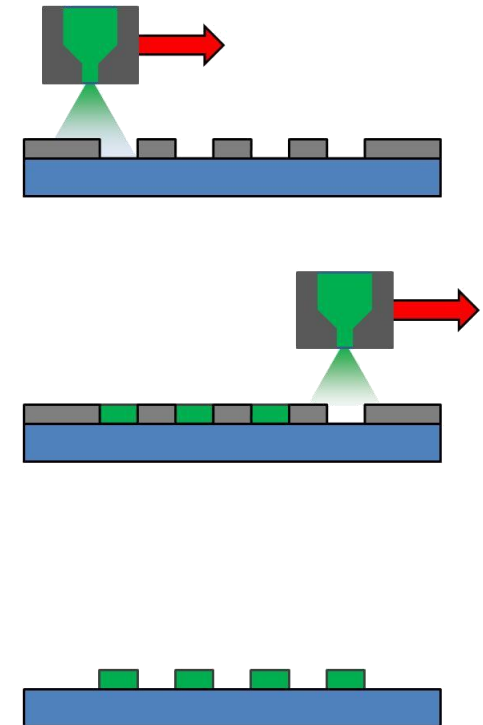


# Additive manufacturing techniques for structured films

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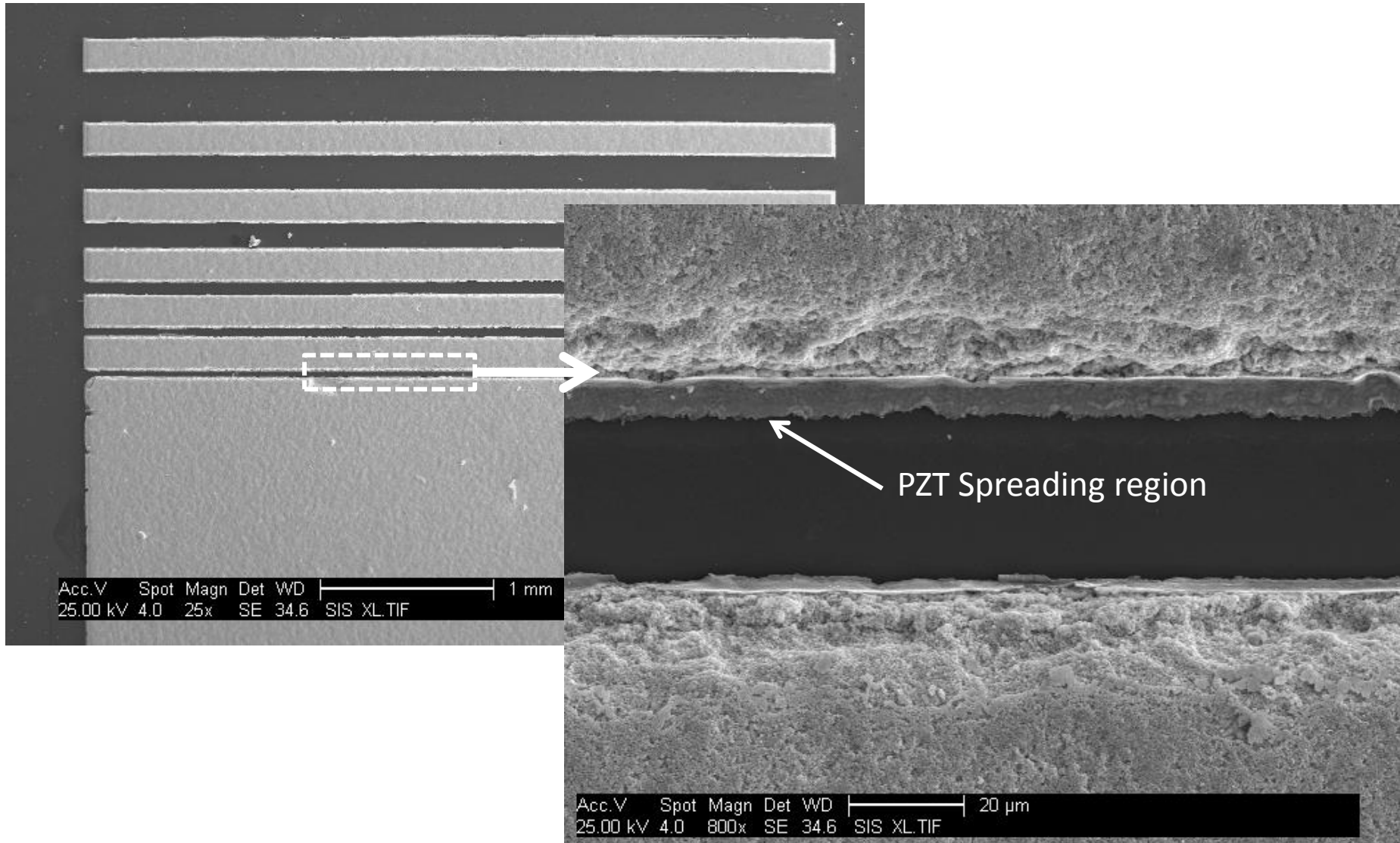


*PZT features created by micro moulding*

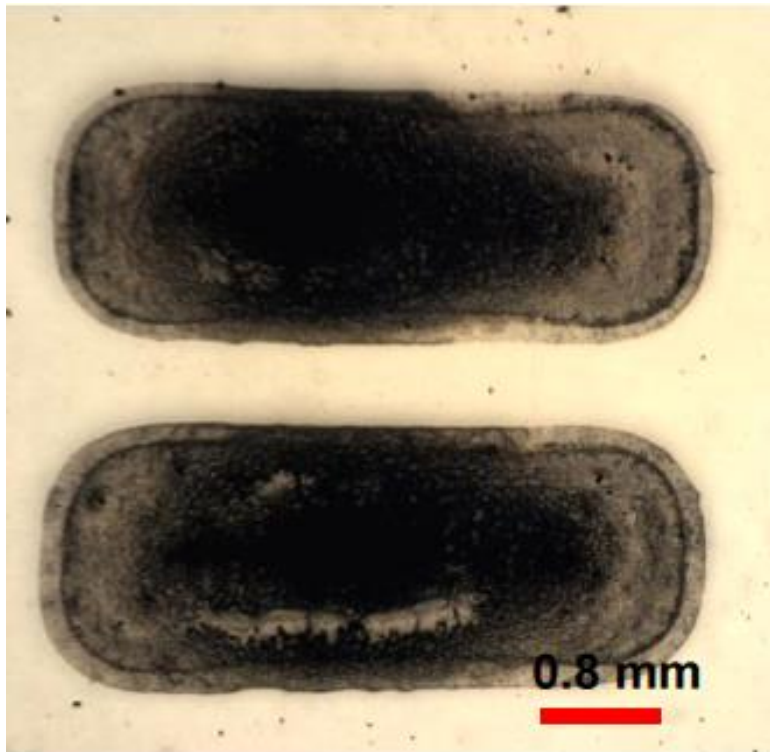


*D. Wang, S.A. Rocks, R.A. Dorey, Micromoulding of PZT film structures using electrohydrodynamic atomization mould filling, J.Euro.Ceram.Soc., 29, 1147–1155, 2009. .*

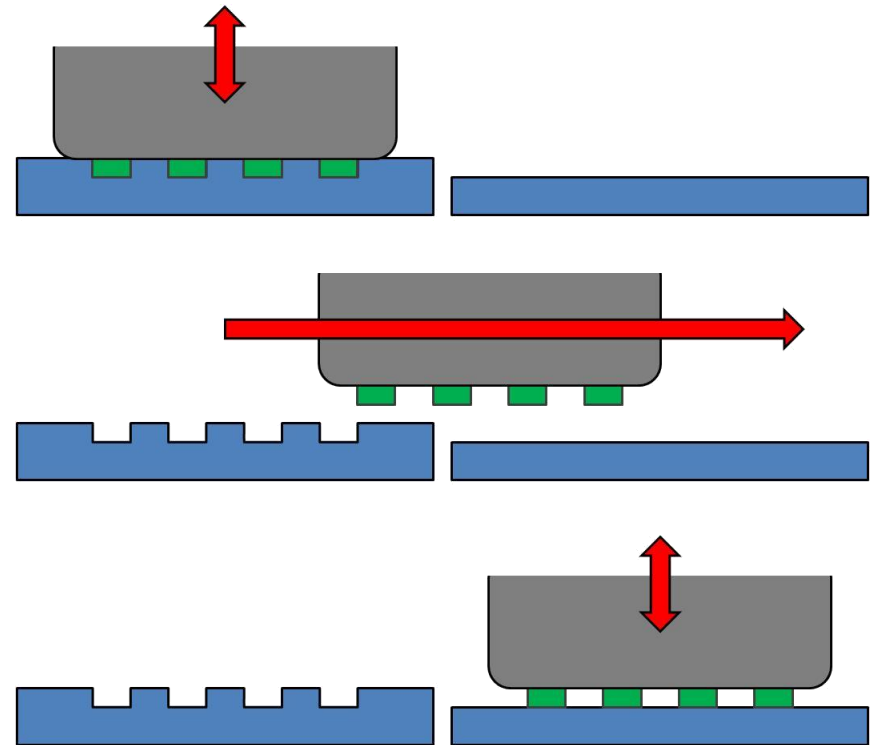
# Structuring – micromoulding



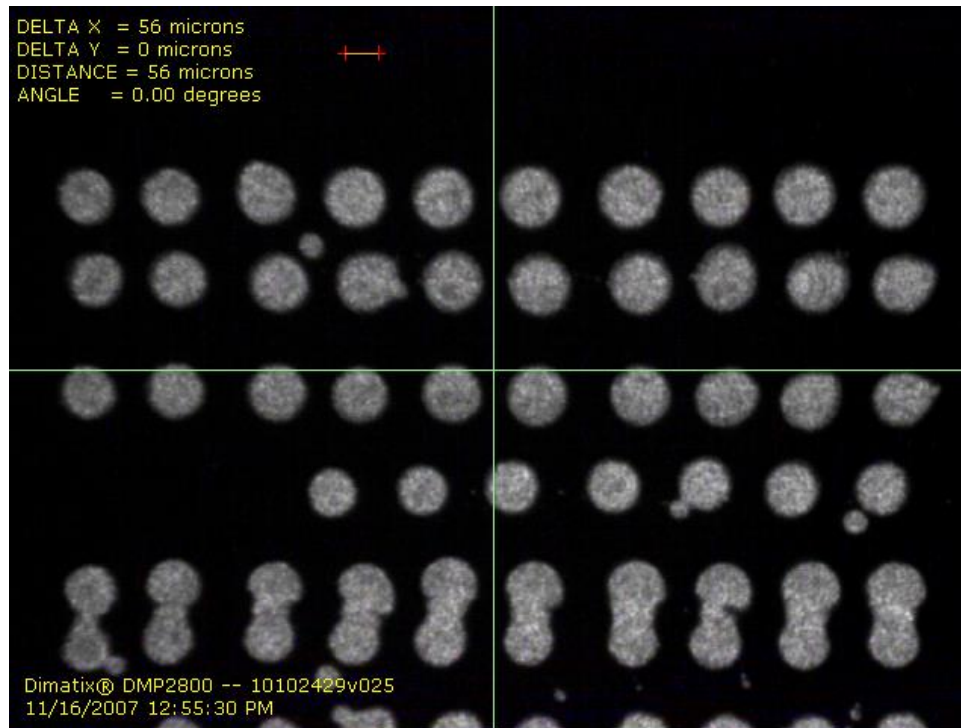
# Structuring – pad printing



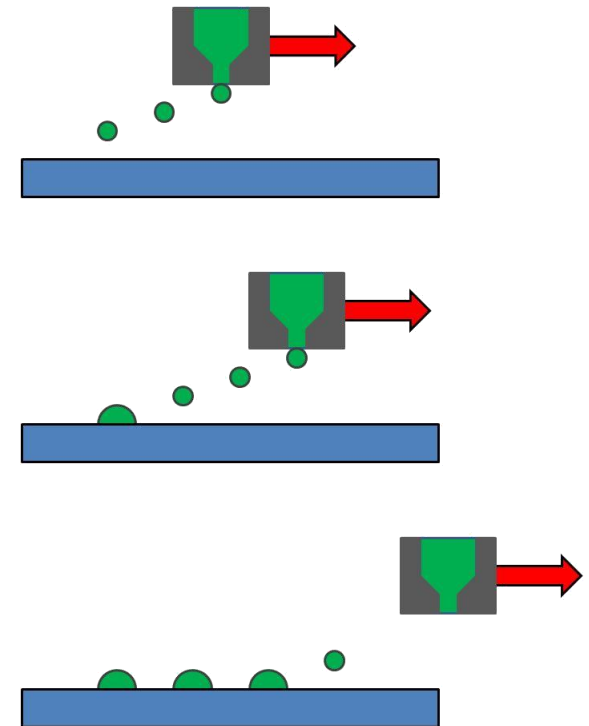
*Silver NPs deposited by pad printing*

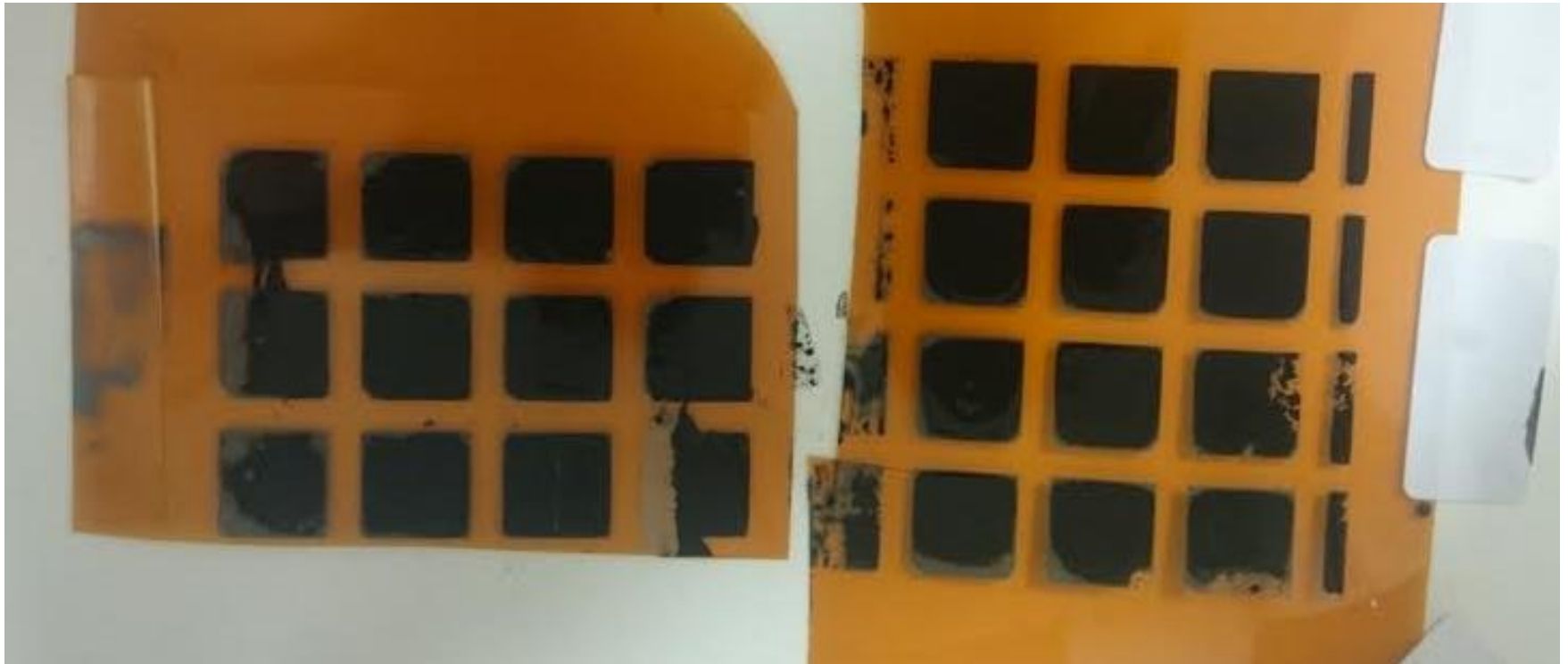


# Structuring – direct writing



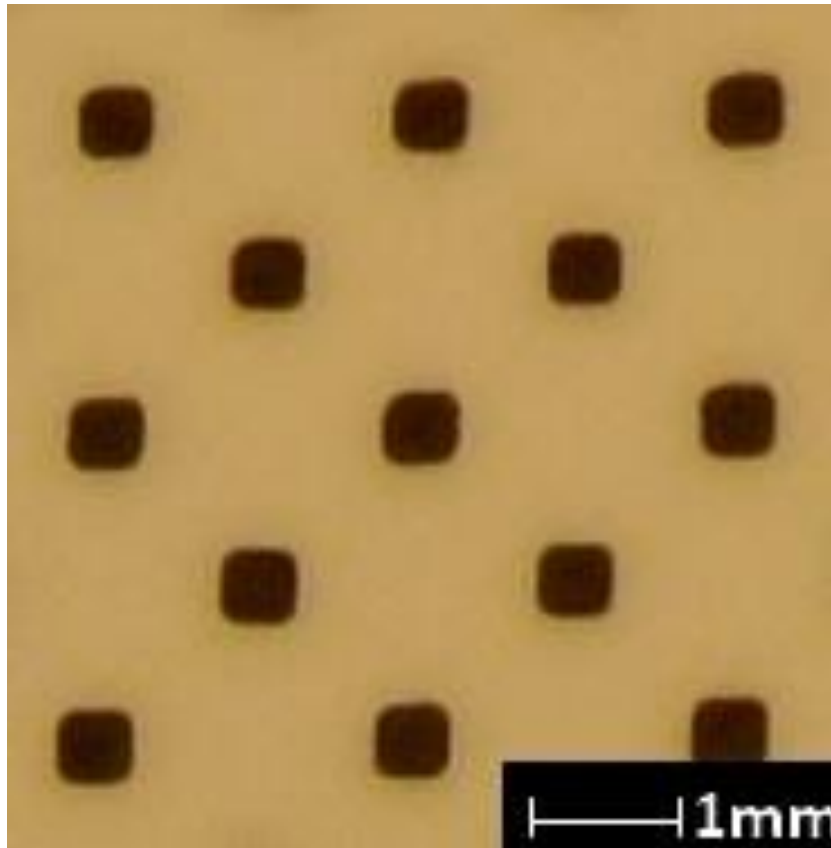
*PZT features created by ink jet printing*



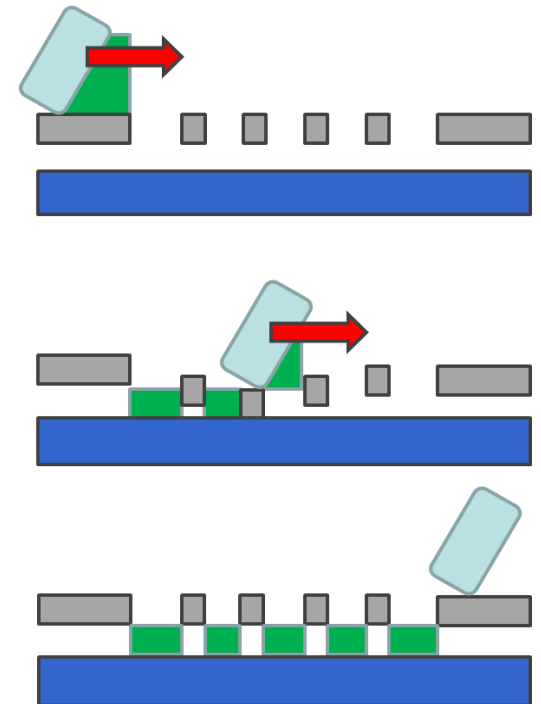


*Bi<sub>2</sub>Te<sub>3</sub> features created by ink jet printing an aqueous ink*

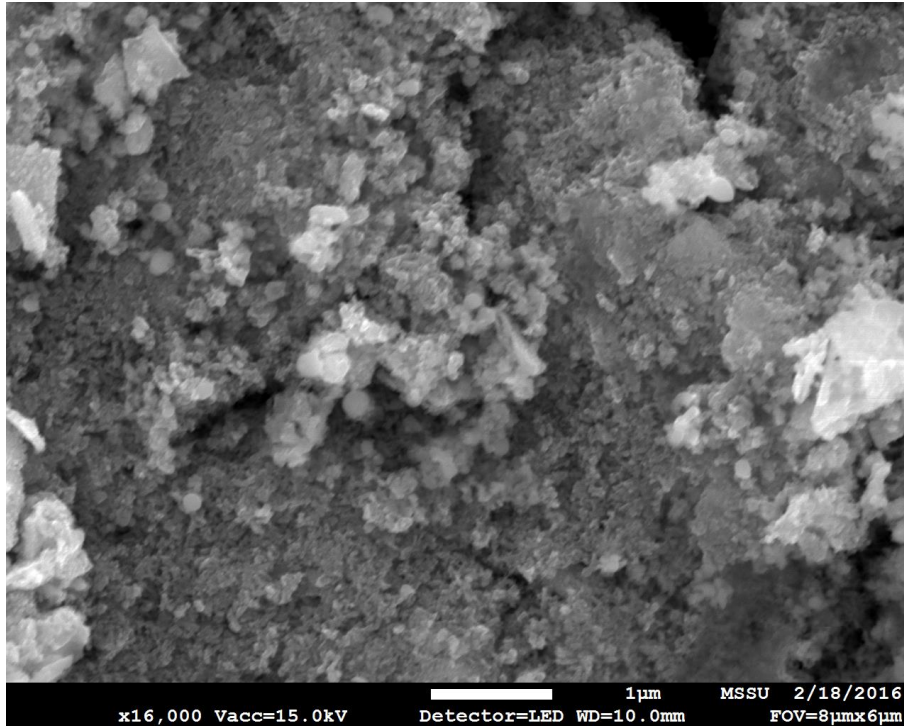
# Deposition – screen printing



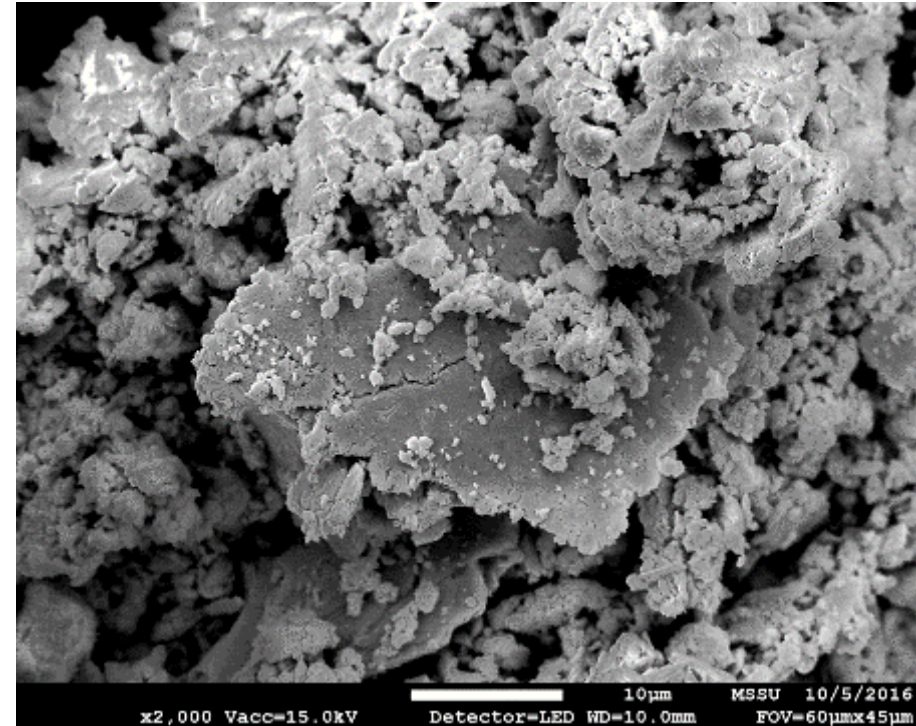
*Bi<sub>2</sub>Te<sub>3</sub> features created by screen printing*



# Structuring – direct writing



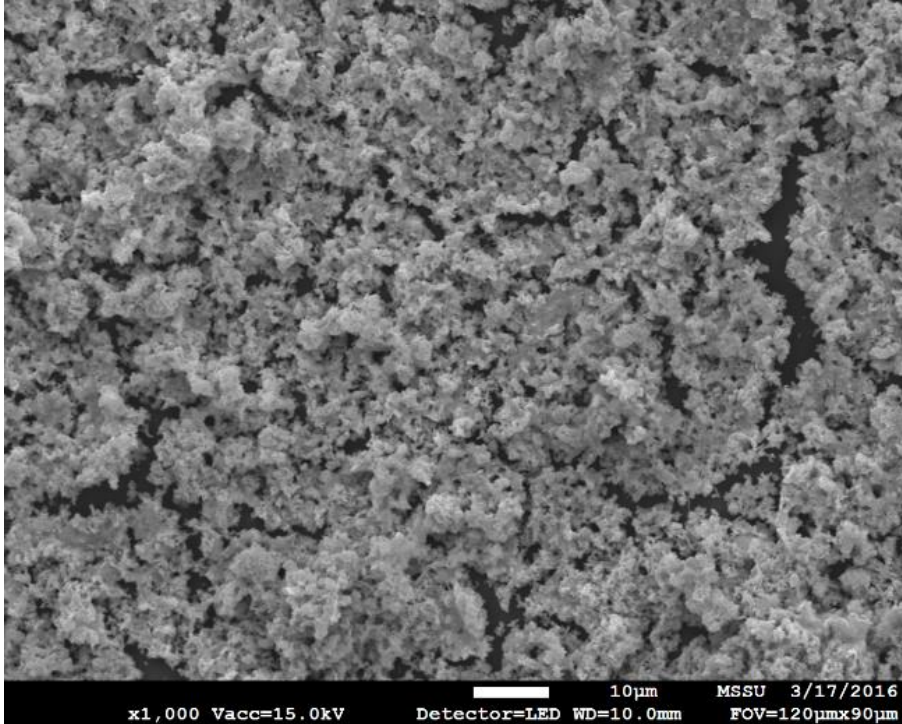
*Bi<sub>2</sub>Te<sub>3</sub> powder prepared for ink jet printing*



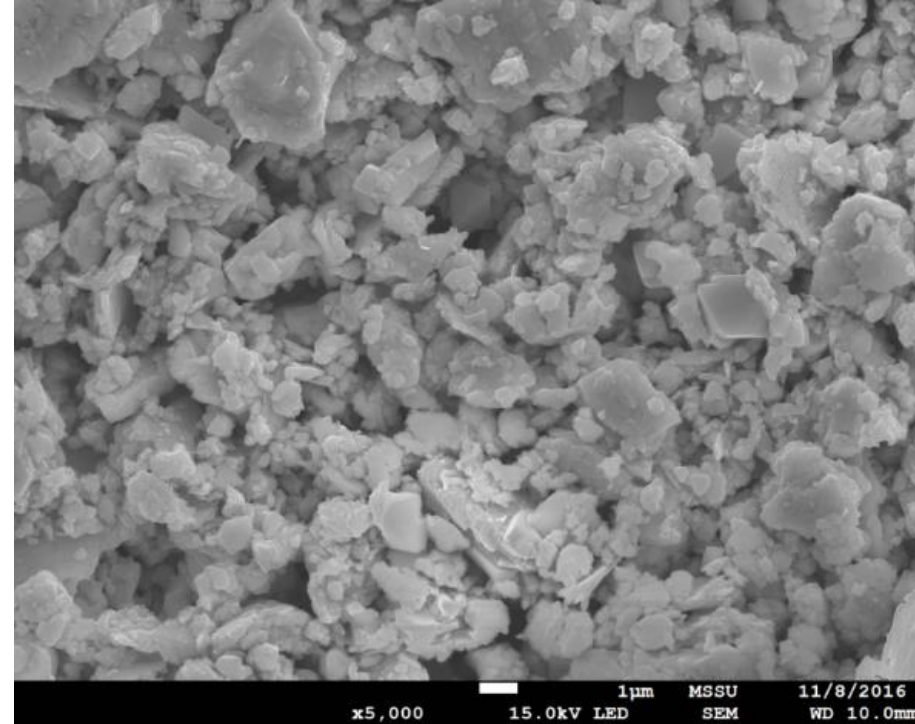
*Sb<sub>2</sub>Te<sub>3</sub> powder prepared for screen printing*



# Structuring – direct writing



*Ink jet printed  $\text{Bi}_2\text{Te}_3$*



*screen printed  $\text{Sb}_2\text{Te}_3$*

# Additive manufacturing techniques for structured films

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Design criteria

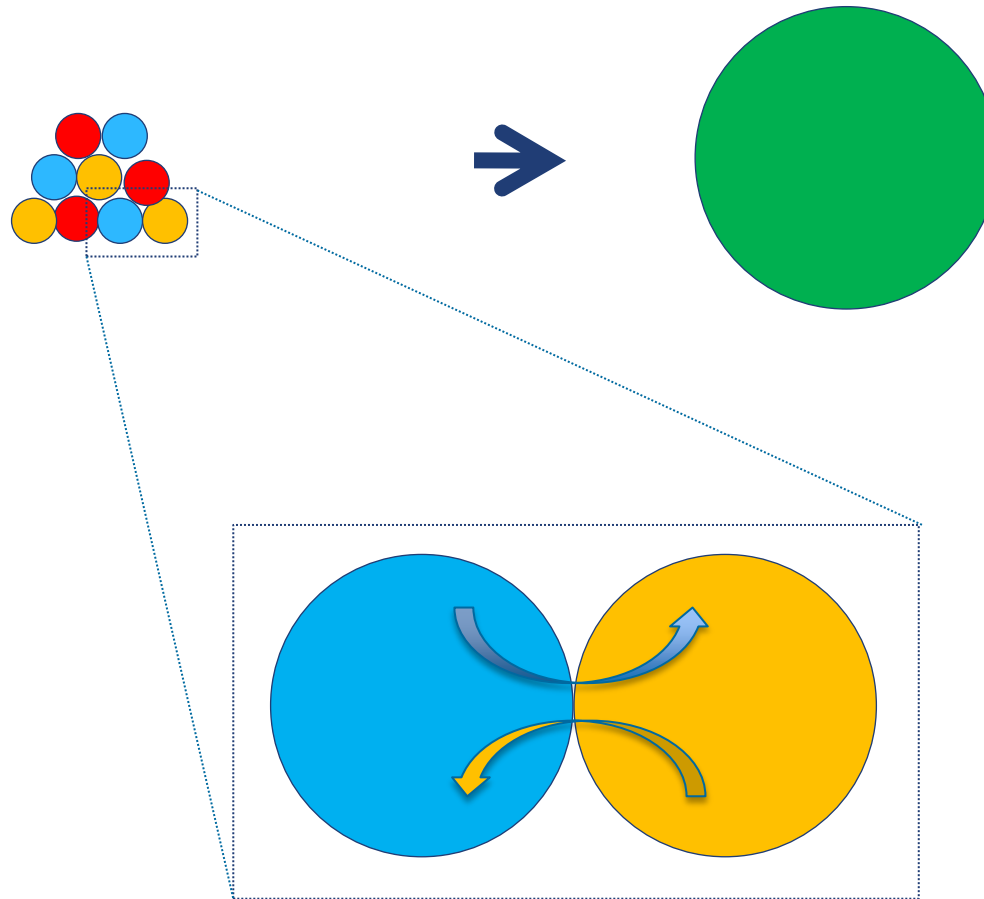
**Building block size  $\ll$  feature size**

# Powder synthesis

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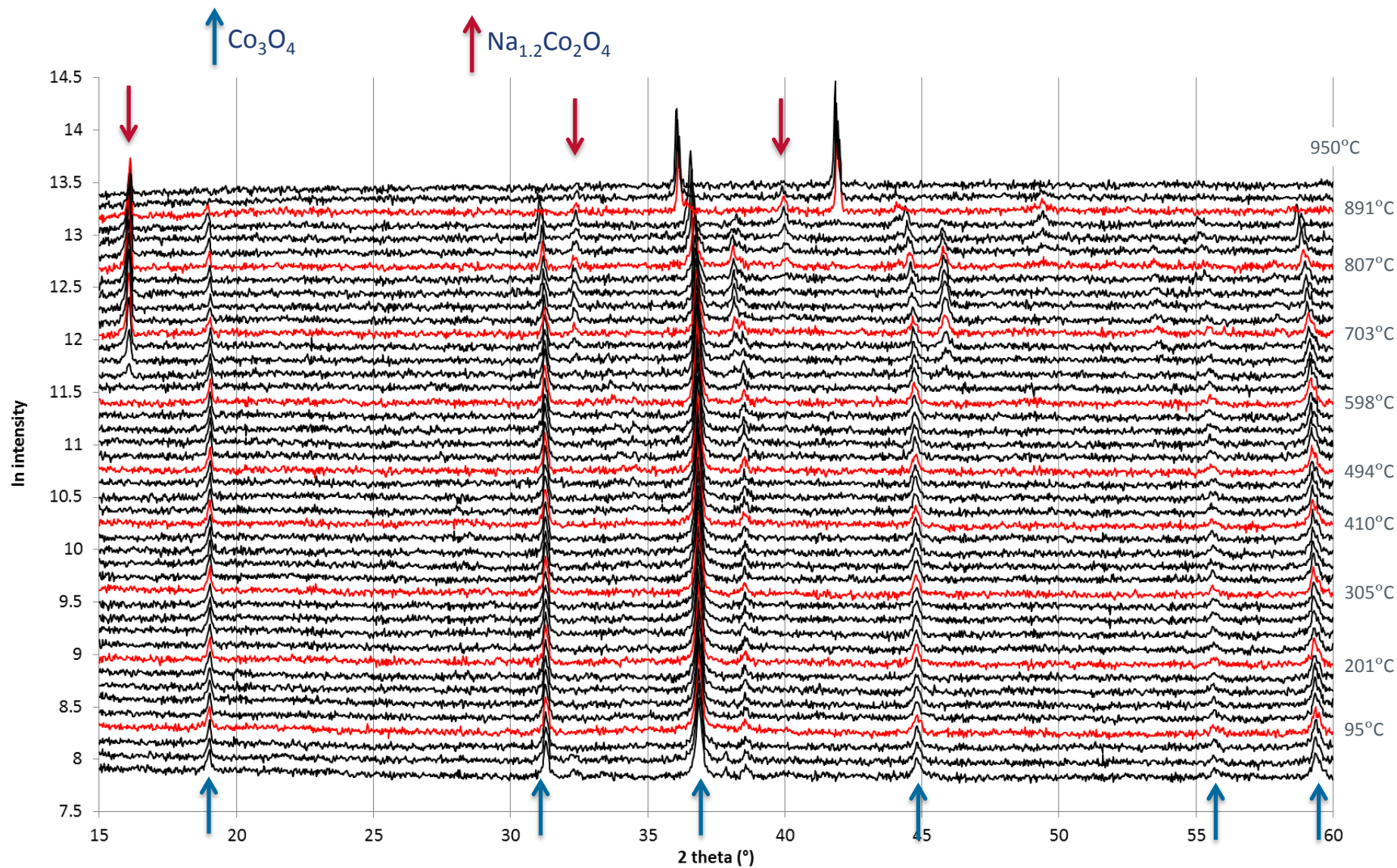
Need small functional (multi-element) materials  
particles

# Fusion based techniques #1: particle growth

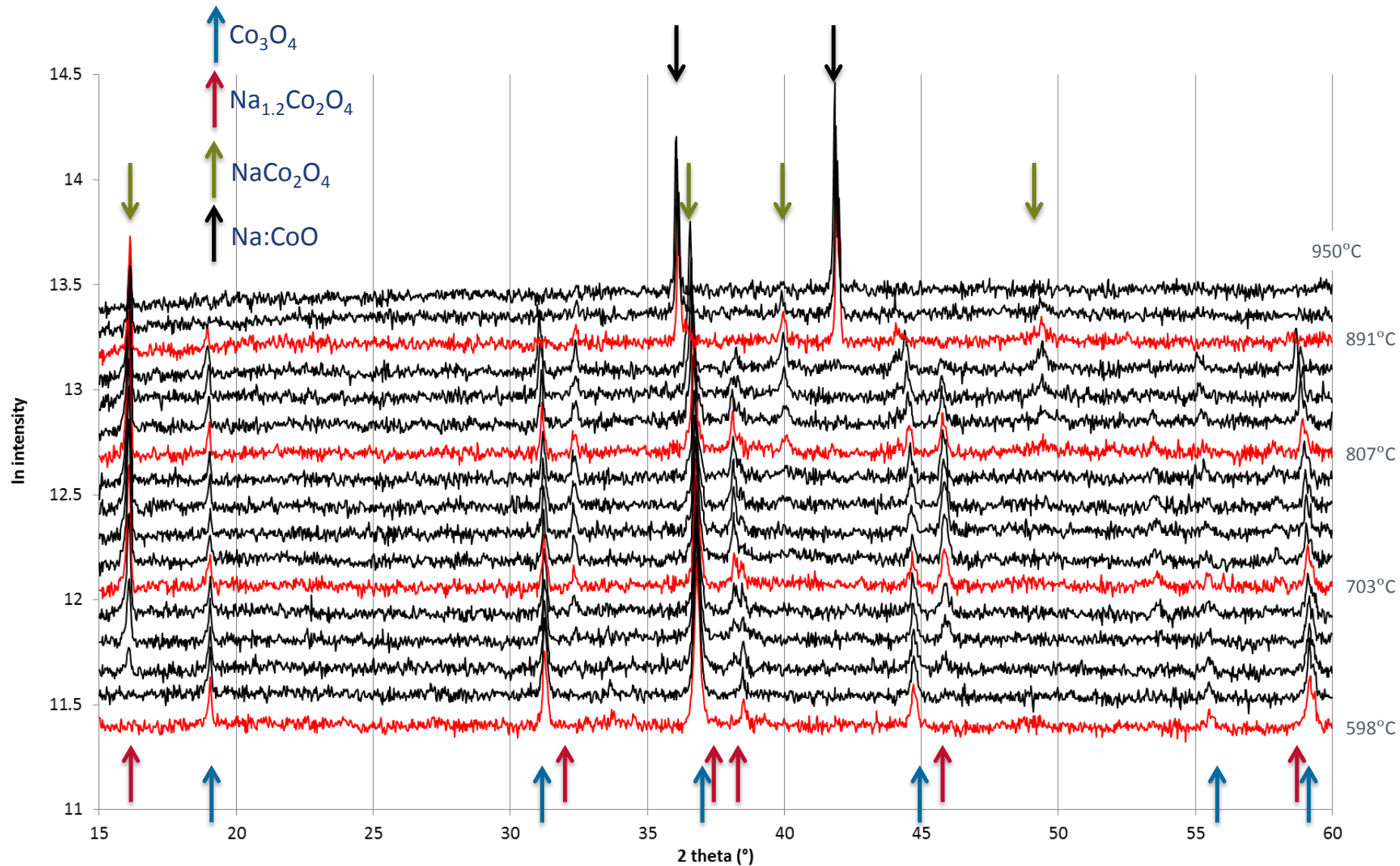


Particle growth due to coalescence of multiple primary particles  
= **Fundamental limit on particle size**

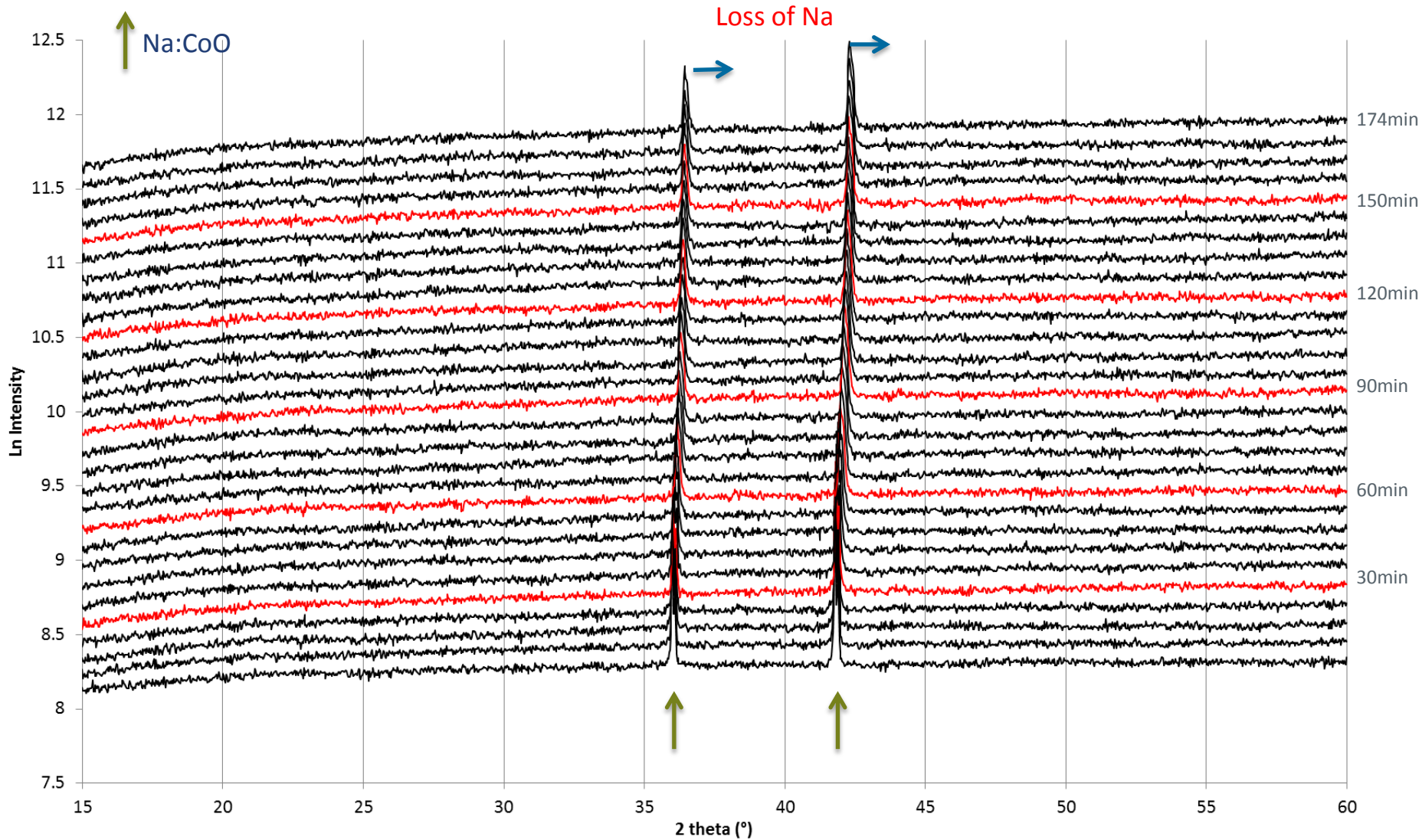
# Fusion based techniques #2: phase evolution



# Fusion based techniques #2: phase evolution



# Fusion based techniques #2: phase evolution (950°C hold)

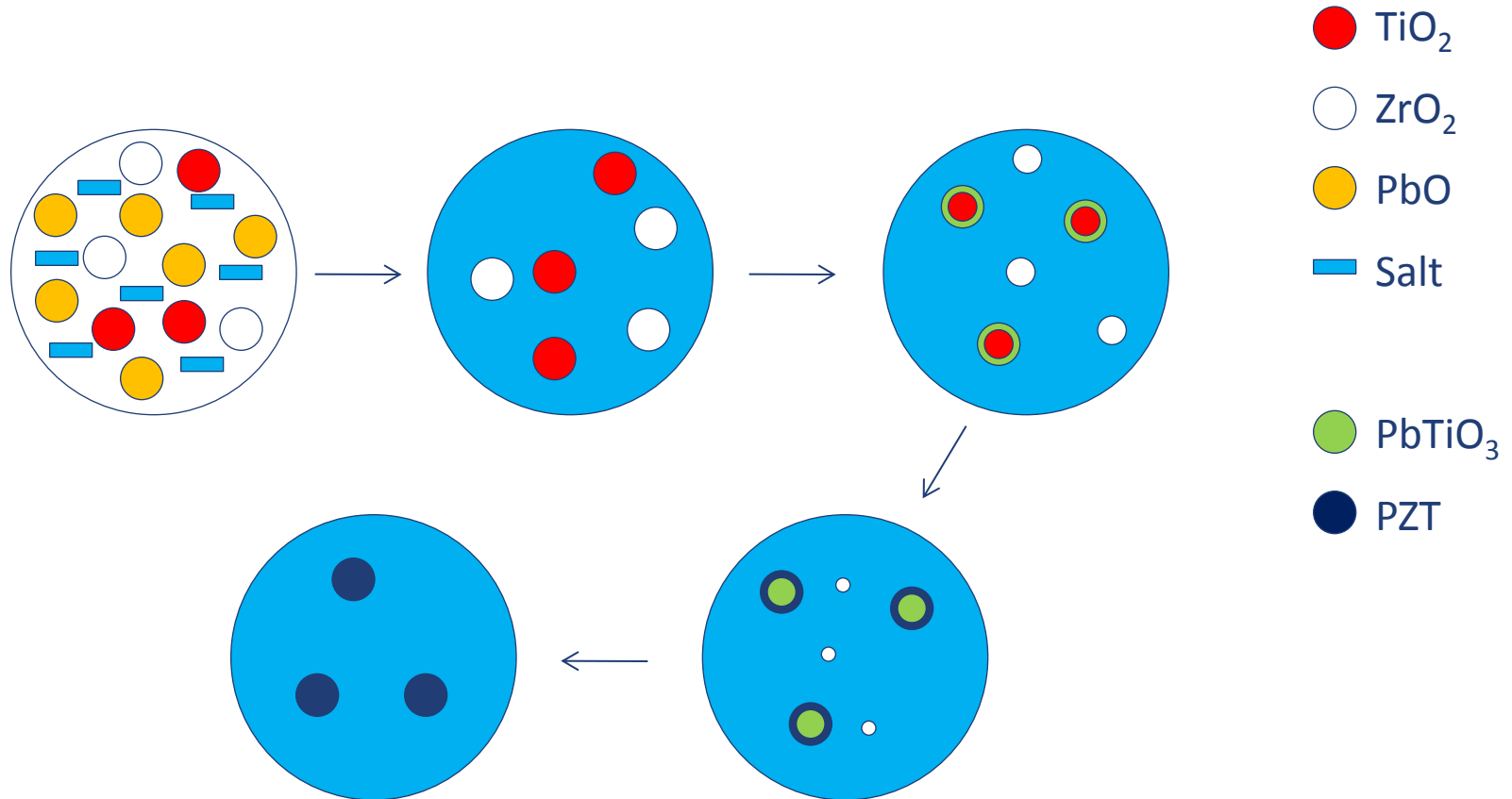


# Powder synthesis

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***Liquid phase/bottom up required***

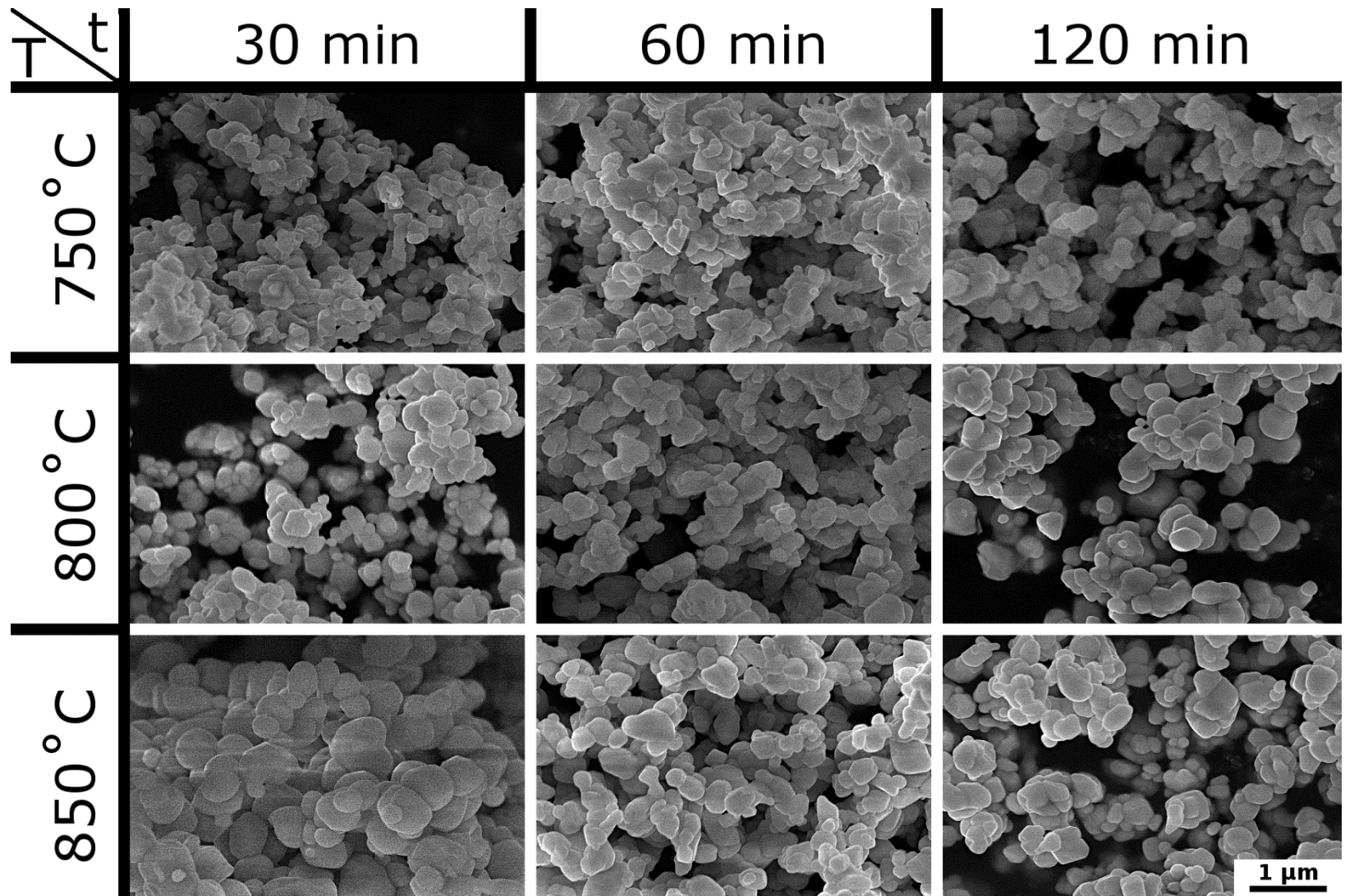




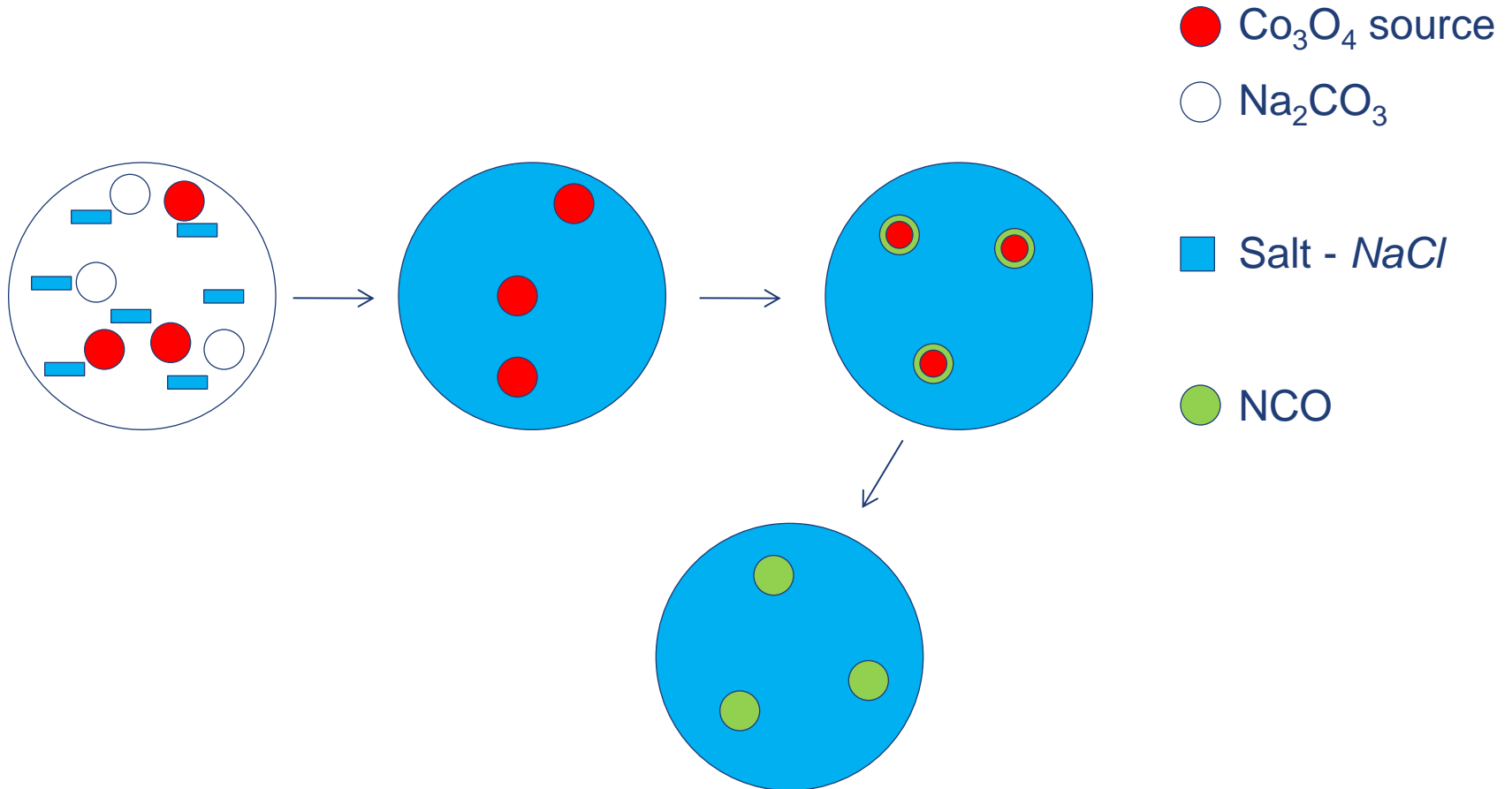
*PbO soluble in NaCl/KCl –  $\text{ZrO}_2$  slight solubility*

*F. Bortolani, R.A. Dorey, Molten salt synthesis of PZT powder for direct write inks,  
J. Euro.Ceram.Soc., 30, 2073-2079, 2010*

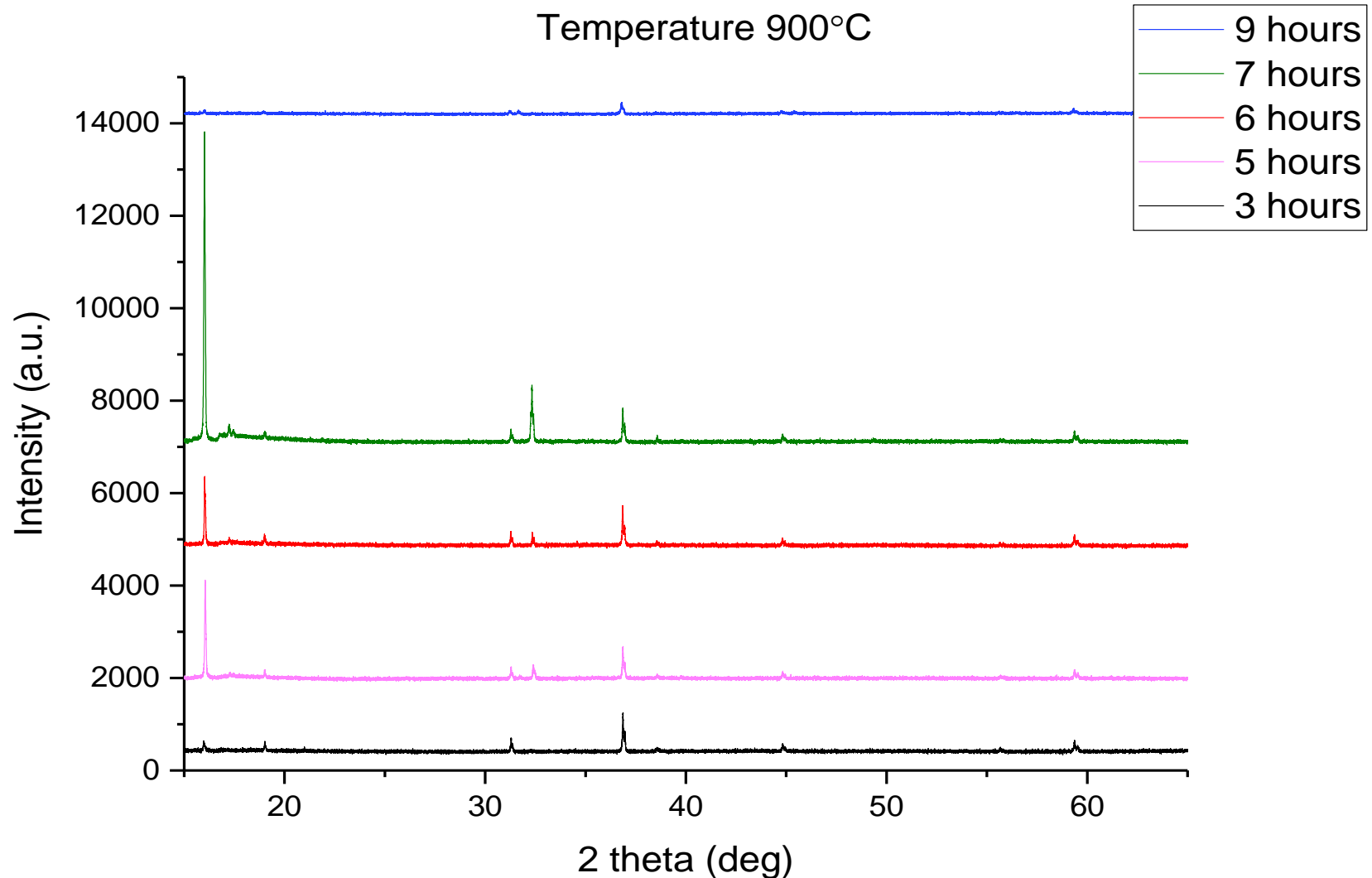
# Molten salt synthesis



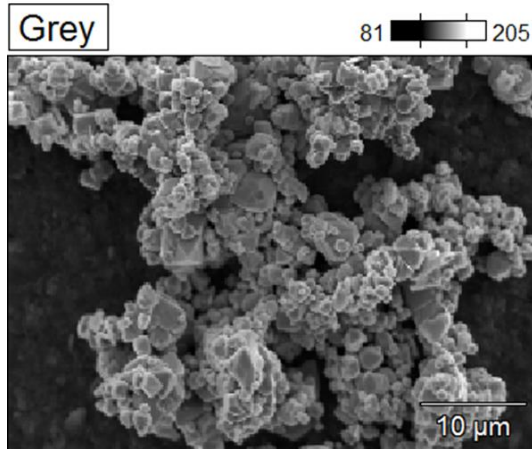
# Molten salt synthesis – $\text{NaCo}_2\text{O}_4$



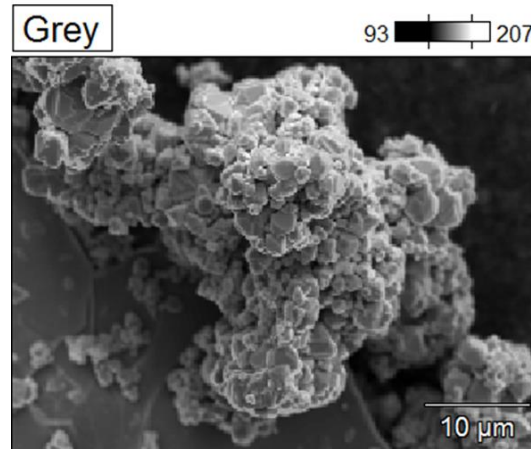
# NaCo<sub>x</sub>O<sub>y</sub> evolution (MSS@900°C)



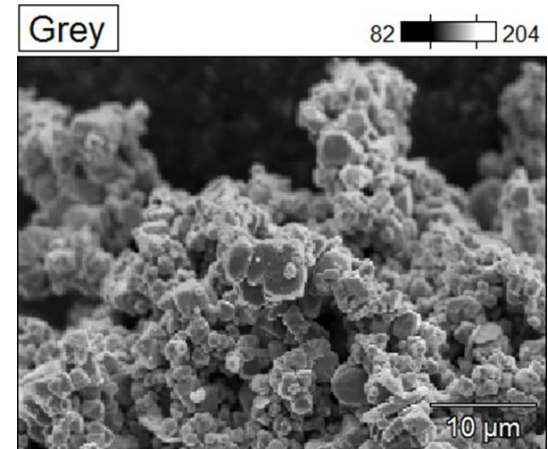
# $\text{NaCo}_x\text{O}_y$ evolution (MSS@900°C)



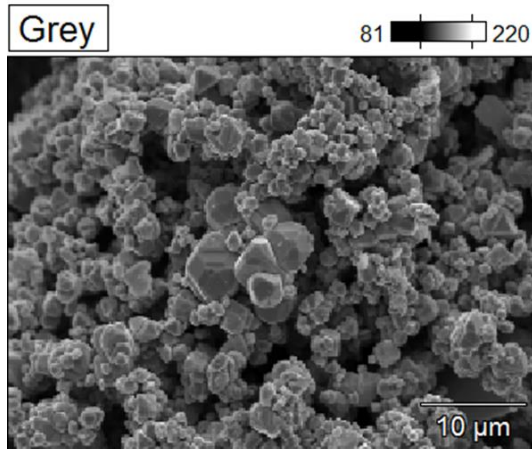
3h



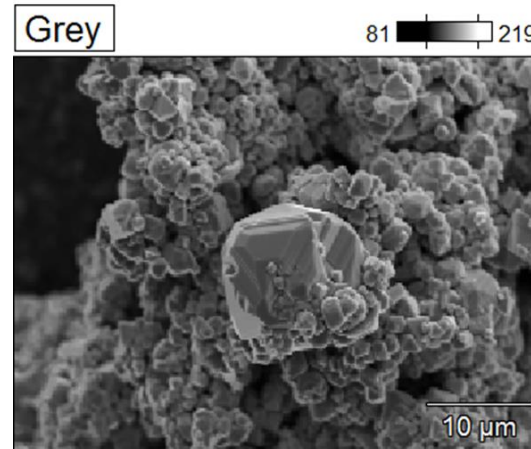
5h



6h



7h

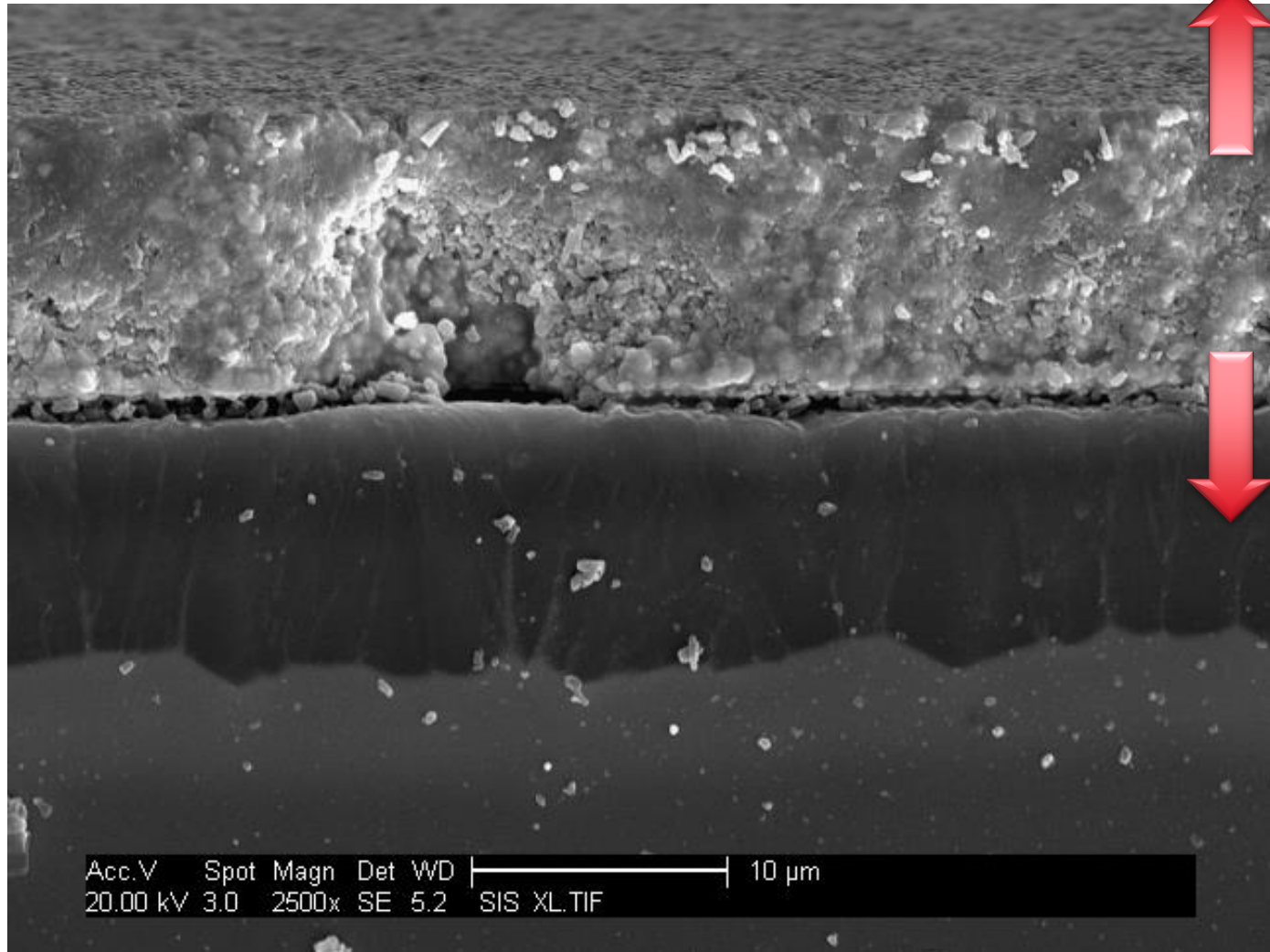


9h

# Processing of films

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# How about films during manufacture?



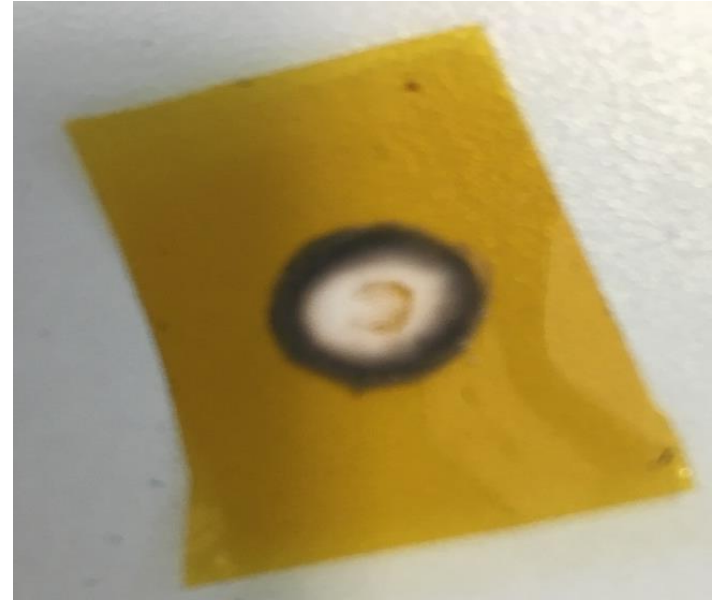
*Cross section of PZT following heat treatment at 800°C for 4 hours*

# $\text{Bi}_2\text{Te}_3$ thick films – reaction with oxygen

10 min at 100°C in air



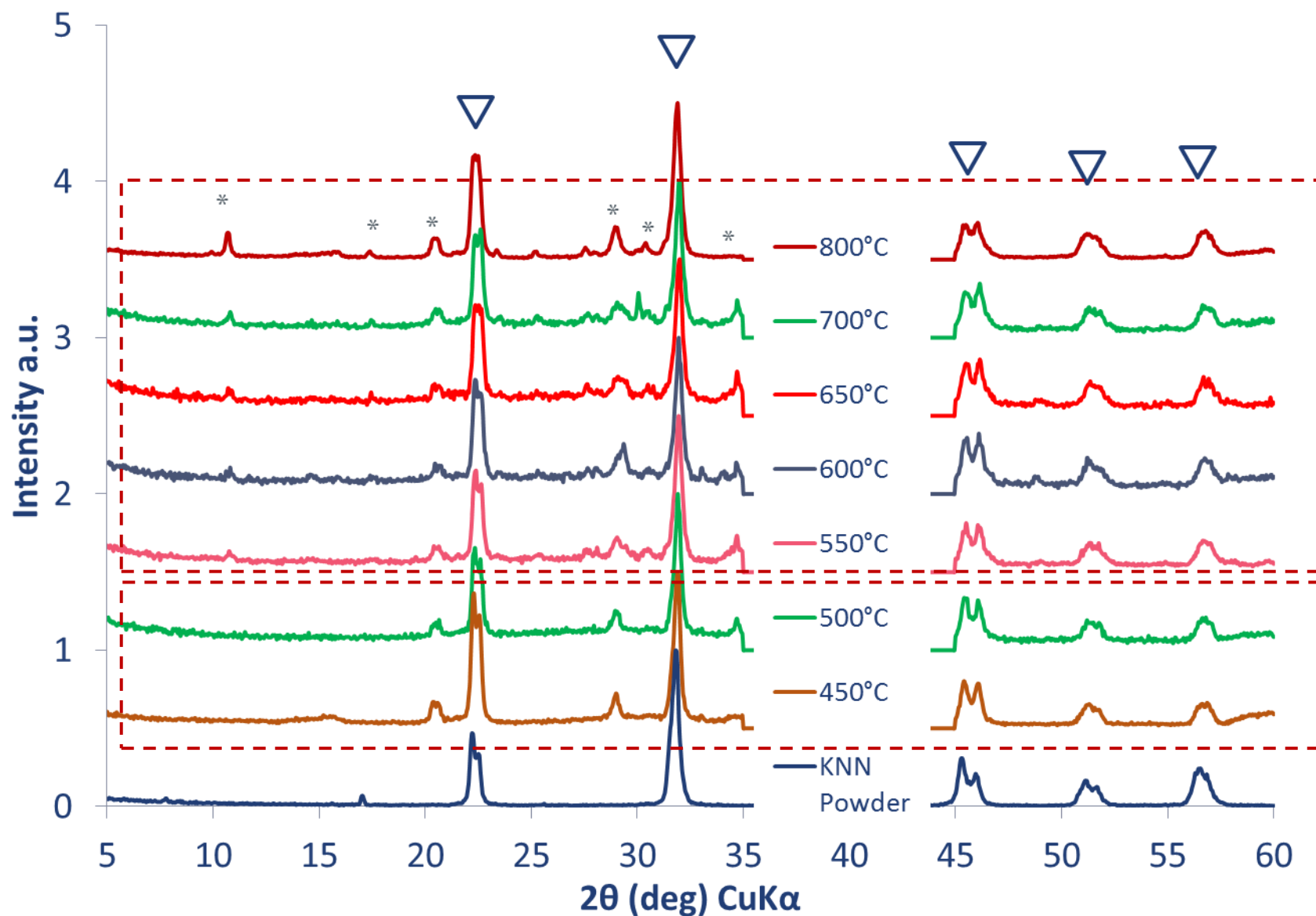
10 min at 350°C in air



Extensive reaction with atmosphere oxygen at low temperatures



# KNN thick films - challenges

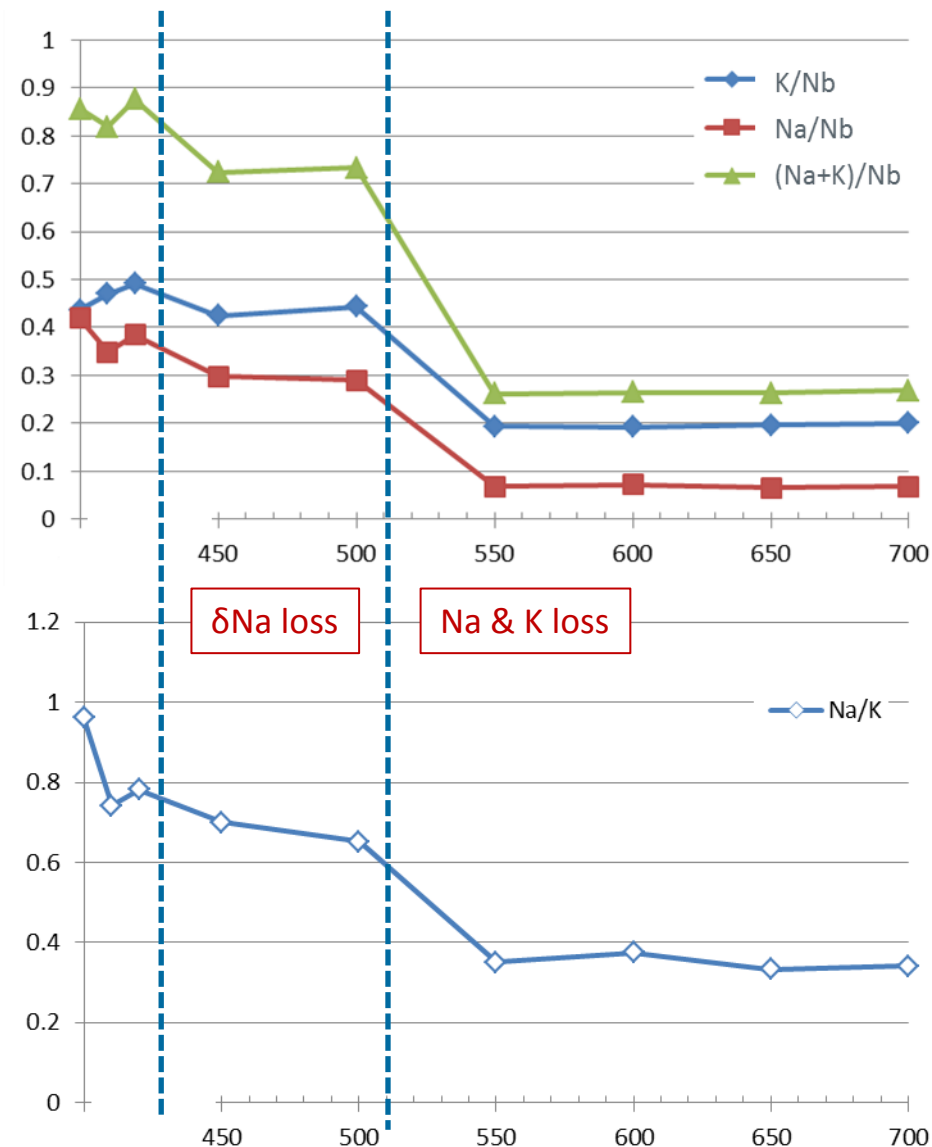


# KNN thick films – loss of volatile elements



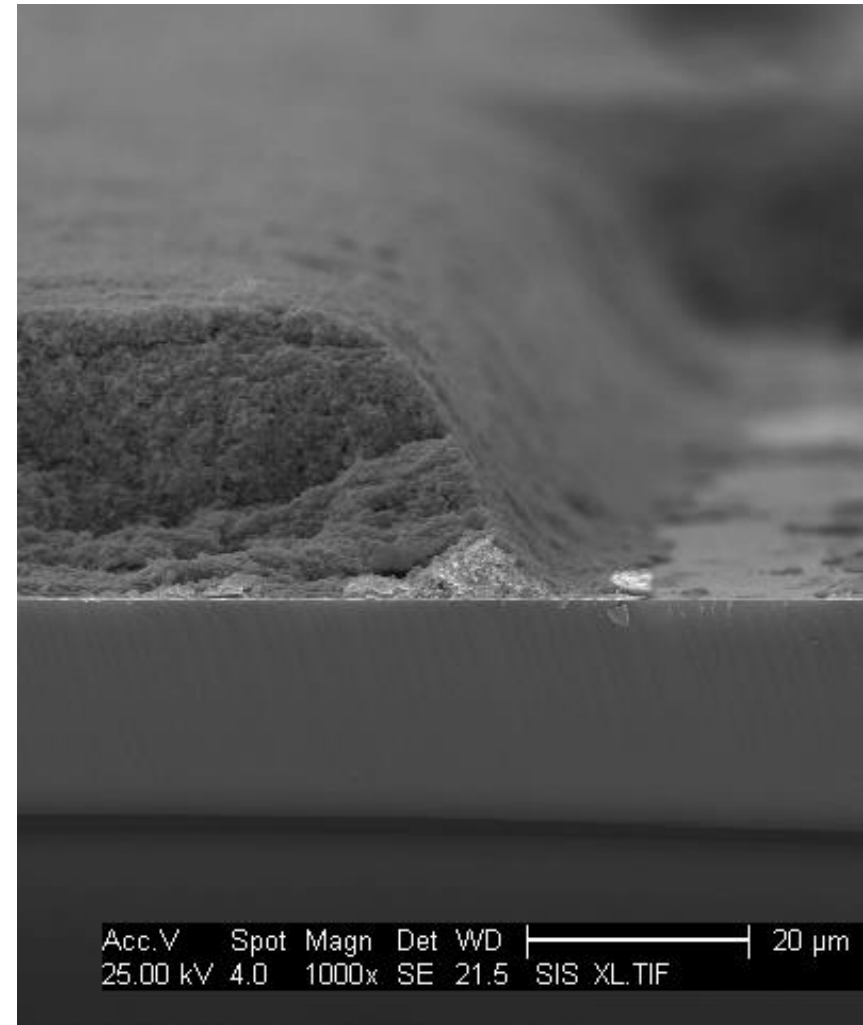
	Na At%	K At%	Nb At%
KNN Powder	22.6	23.5	53.9
Dried KNN sol	19.17	25.83	55
After deposition*	20.5	26.2	53.3
450°C/30 min	17.3	24.7	58.1
500°C/30 min	16.7	25.6	57.7
550°C/30 min	5.4	15.4	79.3
600°C/30 min	5.7	15.2	79.1
650°C/30 min	5.2	15.6	79.2
700°C/30 min	5.4	15.8	78.8

\*200°C/1 min & 450°C/30 sec



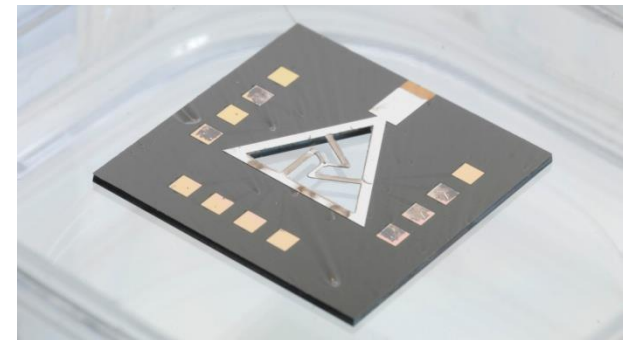
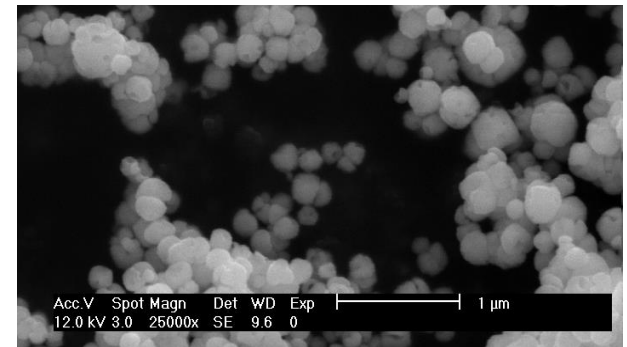
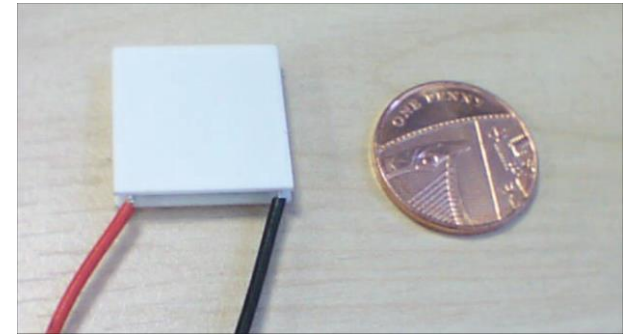
## How about films during manufacture?

- Compositional fluctuations occur through-thickness of sample
- During early stages of sintering porous nature dominates for oxidation/evaporation effects
- Substrate interactions more important at longer times
- Substrate interactions lead to compositional gradient (*inward & outward diffusion*)
- Pattern has little effect provided aspect ratio  $> 1$



# Summary

- Film forming techniques are continually improving
- Cheaper & quicker to fabricate than bulk systems
- Thick films are reliant on consolidation of powders  
i.e. heat required
- Control of content of volatile elements difficult to manage at  $T > 900^{\circ}\text{C}$  without containment & excess.



*Robert A. Dorey,  
Integrated Powder-based Thick Films for Thermoelectric,  
Pyroelectric and Piezoelectric Energy Harvesting Devices  
IEEE Sensors Journal, vol 14, no 7, pp 2177-2184, 2014*

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